



Microscope Semi APO BF+DF+DIC+PL A13.1095-R Full Auto Reflect Portable Metallurgical

Basic Information

Place of Origin: China

Brand Name: CNOEC, OPTO-EDU

Certification: CE, Rohs
Model Number: A13.1095
Minimum Order Quantity: 1 pc

Price: FOB \$1~1000, Depend on Order Quantity
 Packaging Details: Carton Packing, For Export Transportation

• Delivery Time: 5~20 Days

Payment Terms: T/T, West Union, Paypal

• Supply Ability: 5000 pcs/ Month



Product Specification

Observation Method: Bright Field, Dark Field, Polarizing, DIC

Main Body: ATH Semi-Auto Body + Halogen Illumination

Head: Ergo Tilting Trinocular Head, Inclination

0°~35°

• Eyepiece: SW10x/25mm, High Eyepoint, Diopter

Adjustable, Dia.30mm

Nosepiece: Auto Coded Nosepiece, Sextuple, Backward

Objective: Infinity Plan BF/DF Semi-APO Metallurgical

Objective

• Highlight: digital trinocular microscope,

usb digital microscope



Shortcut Buttons

With this shortcut button, the user could switch 2 preseted objectives fast. Also, this shortcut button could be set with other functions by user.

More Images





Research Level Metallurgical Microscope Semi-Auto, With Reflect, Transmit/Reflect Light
Manual 6 Holes Nosepiece With NIS45 Infinity Plan Semi-APO BD Objective 5x10x LWD 20x50x100x
4" Working Stage, Size 210x170mm, Move Range 102x102mm, With Round Crystal Holder, Wafer Holder Etc.
Reflect 12V100W Halogen Illuminator, Bright Field, Polarizing, DIC View

Transmit 12V100W Halogen Kohler Illumination, Auto Adjust Brightness, ECO Function



OPTO-EDU (BEIJING) CO., LTD.

F-1501 Wanda Plaza, No.18 Shijingshan Road, Beijing 100043, China Tel:+8610 88696020 Fax:+8610 88696085

A13.1095

Metallurgical Microscope, Full Auto, Reflect, Transmit/Reflect, Semi-APO,



A13.1093, A13.1095 Series Microscope



Product Details







A5M.1091, A5M1092 Series Infinity Plan BF/DF Semi-APO Objectives

By using carefully selected high-transparent glass and advanced coating technology, A5M.1091 objective lens can provide high resolution image and accurately reproduce the natural color of the specimen. For special applications, a variety of objectives is available, including polarizing and long working distance.

Focusing System In order to make the system suitable for the operating habits of the operators, the knob of focusing and stage can be adjusted to the left-hand side or right-hand side. This design makes the operation comfortable



Remote Control Pad

Objectives could be switched by simply pressing the rotating buttons. Users could also self-define two of the most commonly used objectives. User could swap between these two objectives by pressing the green button.



Motorized X/Y/Z Working Stage

A54.1095 micro electric control platform provides control movement in three directions of XY/Z. The stepper motor and screw rod mode is adopted to ensure the flatness and accuracy of the XY axis movement, and the maximum scanning speed can reach 25mm/s. Through software control, it can process microscopic shooting automation and process pictures, such as image stitching, depth-of-field fusion (need to match the electric Z-axis), perforated plate scanning, etc.





A13.1095 Meta+A1:E75lect, Semi-APO, BF+DF+DIC+PL		A13.1095		Cata.No.
7 10.1033 WC	atar.E70loot, Octili Al O, Bi +Bi +BiO+i E	-R	-TR	
Optical System	NIS45 Infinite Optical System	•	•	
Observation Method	Bright Field	•	•	
	Dark Field	•	•	
	Polarizing	•	•	

	DIC	•	•	
Main Body	BH Manual Body + Halogen Illumination.			A54.1090 BH
	BL Manual Body + LED Illumination.			A54.1090- BL
	ATH Semi-Auto Body + Halogen Illumination. Auto Nosepiece + Auto Condenser + Auto Brightness Adjust	•	•	A54.1090 ATH
	ATL Semi-Auto Body + LED Illumination. Auto Nosepiece + Auto Condenser + Auto Brightness Adjust	0	0	A54.1090 ATL
	Seidentopf Binocular Head, Inclined 30°, Interpupillary Distance 47-78mm	0	0	A53.1090 B
Head	Seidentopf Trinocular Head, Inclined 30°, Interpupillary Distance 47-78mm, 3 Level Ligth Split Switch E100:P0/E20:P80/E0:P100	0	0	A53.1090 T
	Ergo Tilting Trinocular Head, Inclination 0°~35°, Interpupillary Distance 47-78mm, 3 Level Ligth Split Switch E100:P0/E20:P80/E0:P100	•	•	A53.1090 TT
	SW10x/25mm, High Eyepoint, Diopter Adjustable, Dia.30mm	••	••	A51.1090 1025
	SW10x/22mm, High Eyepoint, Diopter Adjustable, Dia.30mm	0	0	A51.1090 1022
Eyepiece	EW12.5x/16mm, High Eyepoint	0	0	A51.1090 12516
	WF15x/16mm, High Eyepoint, Diopter Adjustable, Dia.30mm	0	0	A51.1090 1516
	WF20x/12mm, High Eyepoint, Diopter Adjustable, Dia.30mm	0	0	A51.1090 2012
	Manual Nosepiece, Sextuple, Backward			A54.1091 6M
	Coded Nosepiece, Sextuple, Backward, For Auto Brightness Adjust			A54.1091 6C
Nosepiece	Auto Coded Nosepiece, Sextuple, Backward, Motorized Switch Objectives, Controled By: 1. Shortcut Button On Right Side Of Base, Can Switch 2 Preseted Objectives Quickly 2. Remote Control Pad In Front Of Base, Press Each Button To Switch Objectives And Adjust The Light Intensity Automatically. 2 Buttons Can Be Self-Defined For Most Commonly Used Objecives, Press Green Button Can Swap Between Them	•	•	A54.1091 6A
	With Slot For Polarizing Compensator Slider Or DIC Slider	•	•	
	Protect Cover For Nosepiece Holes	•	•	A54.1091 C
	BD 5x/0.15, W.D.20mm, No Cover Glass	•	•	A5M.109 ⁻ 5
NIS45 N- MPFN	BD 10x/0.3, W.D.11mm, No Cover Glass	•	•	A5M.109 ⁻
Infinity Plan BF/DF Semi-	BD 20x/0.45, W.D.3mm, No Cover Glass	0	0	A5M.109 ⁻ 20A
APO Metallurgical	BD LWD 20x/0.4, W.D.12mm, No Cover Glass	•	•	A5M.109 ⁻ 20
Objective	BD LWD 50x/0.5, W.D.10.6mm, No Cover Glass	•	•	A5M.109 ⁻ 50
	LWD 100x/0.8, W.D.3.5mm, No Cover Glass	•	•	A5M.109 ⁻ 100
NIS45	BD 50x/0.8, W.D.1mm, No Cover Glass	0	0	A5M.1092 50
BF/DF APO	BD 100x/0.9, W.D.1mm, No Cover Glass	0	0	A5M.1092
Working Stage For Metallurgical Microscope	Motorized X/Y/Z Working Stage, Size 275x239x44.5mm, Move Range 125x75mm, Minimum step length 0.1um, repeat positioning accuracy ±1.5um, maximum speed 20nm/s, soft limit + mechanical limit + photoelectric switch limit, Z axis repeat positioning accuracy average: ±1.5um, near focus ±0.1um, Z Maximum axis speed 10r/s, three-dimensional controllable remote sensing, four-speed speed, USB2.0 & RS232 communication interface, communication speed 9600, Including Control Stick, Controller Box	•	•	A54.1095
Condenser	LWD Condenser, N.A.0.65, W.D.10.2mm, Center Adjustable, Dual Condenser Lifting Handle	•	•	A5M.109

	Coaxial Coarse & Fine Focusing, Fine Division 0.001mm, Focusing Range 35mm, Coarse Stroke 37.7mm, Fine Stroke 0.1mm,Can Exchange Hand	•	•	
Focusing	Wheel Between Left/Righ,			
	Max Sample Space 76mm	•		
	Max Sample Space 56mm	+	•	
	Reflect Epi Metallurgical Illuminator, Turret Disc			
	With 6 Positions For Filter Block, Kohler Illumination	•	•	A5M.1090
Reflect	12V100W Halogen Lamp Housing	•	•	A5M.1090 100W
Light Source	BF/DF View Block	•	•	A5M.1090 BD
	BF1 View Block	•	•	A5M.1090 B1
	BF2 View Block	•	•	A5M.1090 B2
	Filter Blue	•	•	A56.1093 B
Filter For Reflect	Fibler Green	•	•	A56.1093 G
Light Source	Filter Yellow	•	•	A56.1093- Y
	Filter Forested	•	•	A56.1093- F
Polarizing	Polarizer For Reflect Light Source	•	•	A5P.1090 RP
	Analyzer For Reflect Light Source	•	•	A5P.1090 RA
DIC	Blank Slider	•	•	A5P.1090 E
	Nomarski DIC Slider For Reflect Light Source	•	•	A5M.1090 DIC
	Transmit Kohler Illumination, Brightness Adjustable, 12V100W Halogen, External Lamp House		•	A56.1090- 12V100W
	Transmit Kohler Illumination, Brightness Adjustable,		0	A56.1090- 3WLED
	3W S-LED, Built-in Main Body ECO Function Support Auto Power Off After 30			A56.1090-
Transmit	Mins From Operator Leave To Save Energy		•	ECO
Light Source	Auto Brightness Adjust, Brightness For Each Objective Can Be Memorized And Restored When Objective Is Selected			A56.1090
	A13.1095 Upgradeable To Auto Brightness Adjust, Must Upgrade To A54.1091-6C Coded Nosepiece At Same Time		•	AB
	Filter Holder On Base, Can Hold 3 Filters		•	A56.1092 H
	Filter LBD		•	A56.1092 LBD
Filter For Transmit Light	Filter Green		•	A56.1092 G
Source	Filter Yellow		•	A56.1092 Y
	Filter ND6		•	A56.1092 ND6
	Filter ND25		•	A56.1092 ND25
	Eyepiece Adapter Dia.23.2mm	0	0	A55.1090- E
Adapter	C-Mount 1.0x	0	0	A55.1090 1.0x
0. 6	C-Mount 0.5x	0	0	A55.1090 0.5x
Software	NOMIS Basic Image Processiing Software	0	0	A30.1090
	Working Stage Holder Bracket	•	•	A54.1096 A54.1096
	Adapter To Adjust Eye Position	0	0	A1 A54.1096
	Adapter To Lower The Stage Position 1" Immersion Oil	0	0	A2 A50.1090
	Allen Wrench	•		01 A50.1090-
	THIOTE VVICINIE	_	_	02

Other Accessories	Power Cord	•	•	A50.1090- 03
	Short Eye Cover, For Eyepiece	0	0	A50.1090- 04
	Long Eye Cover, For Eyepiece	0	0	A50.1090- 05
	Eyepiece Micrometer, Cross	0	0	A50.1090- 06
	Adapter Ring To Install Eyepiece Micrometer	0	0	A50.1090- 07
	USB Cable	0	0	A50.1090- 08
Note:"●"In Tak	ole Is Standard Outfits."O" Is Optional Accessories "-	" Is Un	availab	le



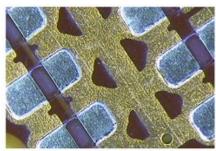


Various Observation Methods

With excellent optical system, A13.1091 series microscope provides high resolution and chromatic aberration corrected images both in the eyepieces and on the monitor.

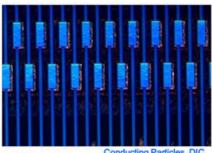
A13.1091 series has been designed with modularity to meet vairous industrial and materials science.

A13.1091 series has been designed with modularity to meet vairous industrial and materials science applications. It gives users flexibility to build a system for specific needs.



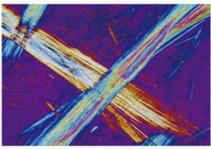
Wafer, Darkfield

Darkfield enables the observation of scattered or diffracted light from the specimen. Anything that is not flat reflects this light while anything that is flat appears dark so imperfections clearly stand out. The user can identify the existence of even a minute scratch or flaw down to the 8nm level-smaller than the resolving power limit of an optical microscope. Darkfield is ideal for detecting minute scratches or flaws on a specimen and examining mirror surface specimens, including wafers.



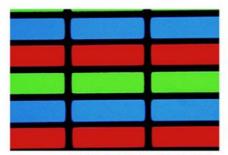
Conducting Particles, DIC

DIC is a microscopic observation technique in which the height difference of a specimen not detectable with brightfield becomes a relief-like or three-dimensional image with improved contrast. This technique utilizes polarized light and can be customized with a choice of three specially designed prisms. It is ideal for examining specimens with very minute height differences, including metallurgical structures, minerals, magnetic heads, hard-disk media, and polished wafer surfaces.



Asbestos, Polarized Light

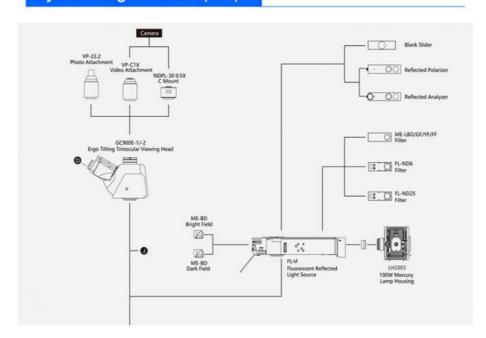
Polarizing Light generated by a set of filters (analyzer and polarizer). The characteristics of the sample directly affect the intensity of the light reflected through the system. It is suitable for metallurgical structures (i.e., growth pattern of graphite on nodular casting iron), minerals, LCDs and, semiconductor materials.

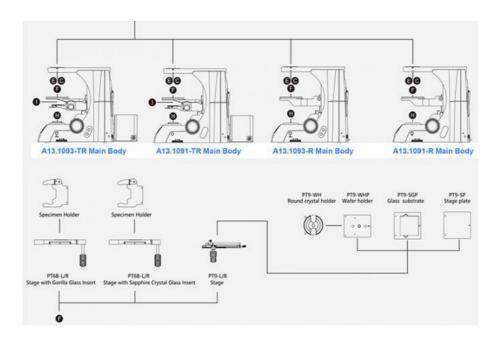


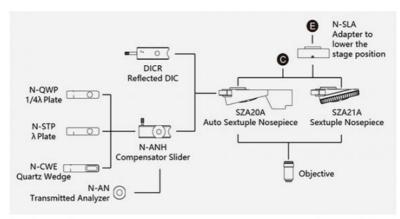
LCD, Transmitted Light Observation

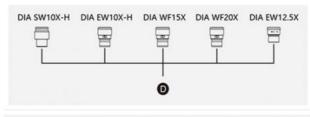
Bright Field Transmit & Reflect View. For transparent specimen such as LCDs, plastics, and glass materials, true transmitted light observation is available by using a variety of condensers. Examining specimen in transmitted brightfield and polarized light can be accomplished all in one convenient system.

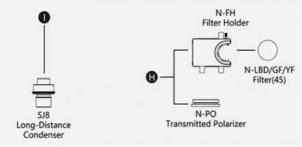
System Diagram & Size(mm)

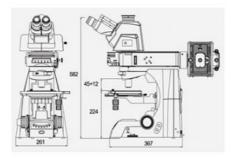


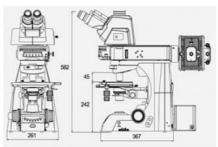












Opto-Edu (Beijing) Co., Ltd.

0086 13911110627



F-1501 Wanda Plaza, No. 18 Shijingshan Road, Beijing 100043, China